

Notice of References Cited	Application/Control No. 10/728,772	Applicant(s)/Patent Under Reexamination RHEE ET AL.	
	Examiner Mahmoud Dahimene	Art Unit 1765	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,413,854	07-2002	Uzoh et al.	438/637
*	B	US-6,303,464	10-2001	Gaw et al.	438/422
*	C	US-6,146,986	11-2000	Wagganer, Eric D.	438/618
*	D	US-2005/0007217	01-2005	Deligianni et al.	335/078
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	S. Wolf and R.N. Ttauber, Silicon Processing for the VLSI Era, Volume 1- Process Technology, Lattice Press, 1986, Page 183.
	V	S. Wolf , Silicon Processing for the VLSI Era, Volume 4- Deep Submicron Process Technology, Lattice Press, 2002, Page 654.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.